



A Practical Approach for Low-Cost Hermetic Lid Sealing

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Outline

- Motivation
- Material system
- Bench top reflow equipment and lid seal process
- LCC reflow experiment
- Results
- Discussion: comparing reflow platforms
- Conclusions and future work



Motivation

- Surface mount leadless chip carrier (LCC)
- Hermetically sealed by reflow of a lead-free solder pre-form
- Large belt-style reflow furnace
 - Mass production of PCBs with surface mount devices
 - 30 to 45-minute cycle time
 - Peak input temperature above 350°C
- An enterprise that assembles low-volume, hermetic LCCs desires:
 - Compact equipment
 - Lower acquisition cost
 - Lesser cycle time
 - Lower energy consumption

Can a practical, low-volume lid seal process with measurable attributes be adapted to compact reflow equipment?

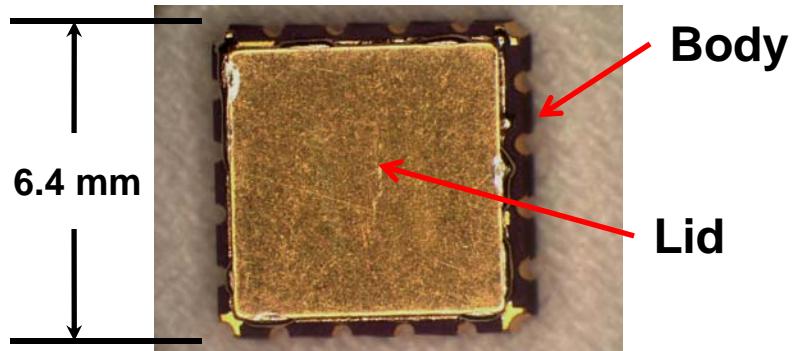
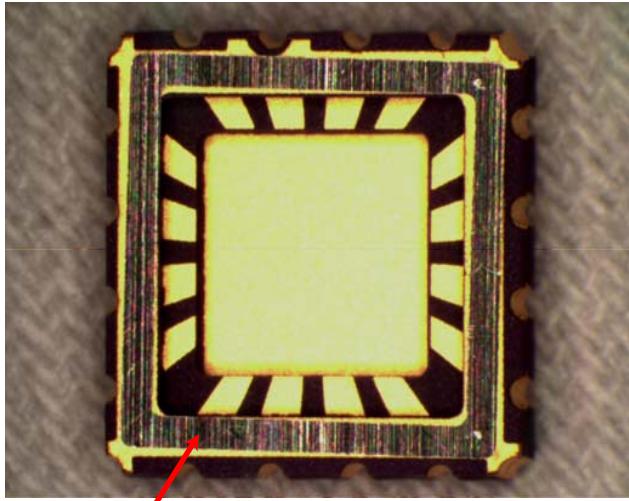


Photo: BTU International Corp.



Material System

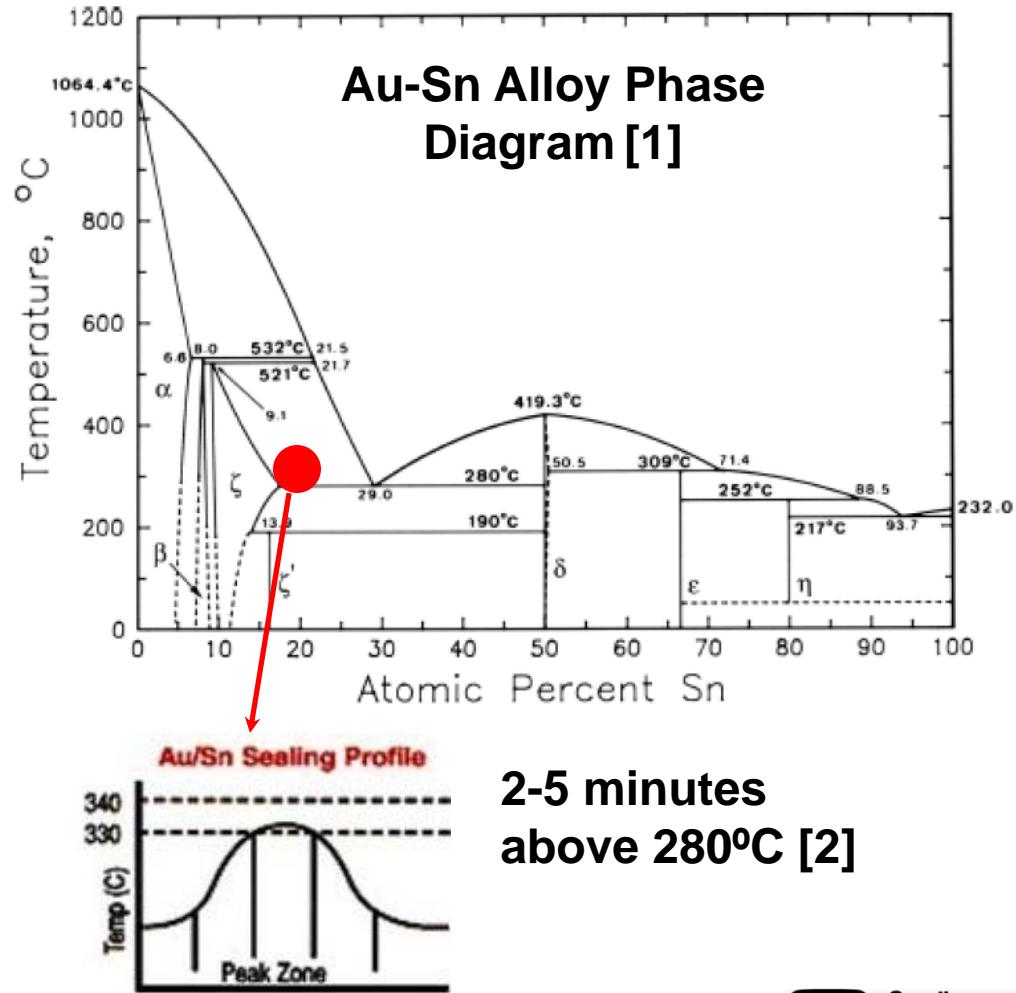


- 80Au-20Sn solder pre-form tacked to lid
- High-temperature co-fired ceramic (HTCC) body
- Seal ring plated with 60 μ in Au on Ni
- Kovar lid with Ni-Au plating

References:

¹ *Processing and Reliability Issues for Eutectic AuSn Solder Joints* in Proceedings 41st International Symposium on Microelectronics (IMAPS 2008), pp. 909-916.

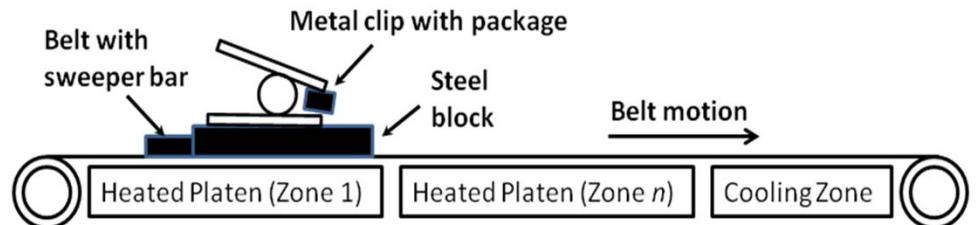
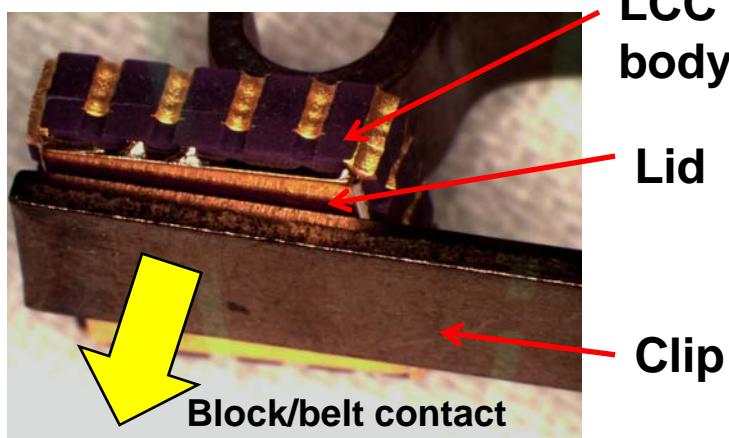
² Materion Corp. (www.materion.com).





Bench Top Reflow Equipment and Lid Seal Process

- Compact dual-mode conduction/convection reflow furnace:
 - 1.2-meter long conveyor
 - Four programmable conduction heating zones
 - Four programmable convection heating zones overhead
 - Cooling stages follow conduction/convection zones.
 - Convection zones flow heated N₂ at 40 sccf/h.
 - Variable gap between opposing zones
- Traditionally for ball attach and surface mount operations.
- Multiple LCCs oriented horizontally and arranged in parallel on metal block.
- Metal clips hold an Au-plated A42 lid with solder pre-form against package frame.
- Configured with lid facing downward for greater conduction to pre-form.





LCC Reflow Experiment

- Desired profile: greater than 280°C for five minutes max., peak temperature 320°C.
- Seven process trials (three parallel LCC samples per trial)
- Compiled a temperature history for each run.
- Sealed packages underwent visual and x-ray inspection of the seal area
- Fine and gross leak tests per MIL-STD-883G, Method 1014.2

| Trial | Conduction Zone Temps (°C) | Convection Zone Temps (°C) | Conveyor Velocity (mm/s) |
|-------|----------------------------|----------------------------|--------------------------|
| 1 | 200-280-375-375 | 175-245-320-332 | 2.96 |
| 2 | 200-280-375-375 | 175-245-320-332 | 2.54 |
| 3 | 200-280-360-360 | 175-245-320-332 | 2.54 |
| 4 | 200-280-350-350 | 175-245-320-332 | 2.54 |
| 5 | 200-280-340-340 | 175-245-300-315 | 2.12 |
| 6 | 200-280-340-340 | 175-245-300-315 | 2.54 |
| 7 | 200-280-340-340 | 200-230-340-340 | 2.12 |

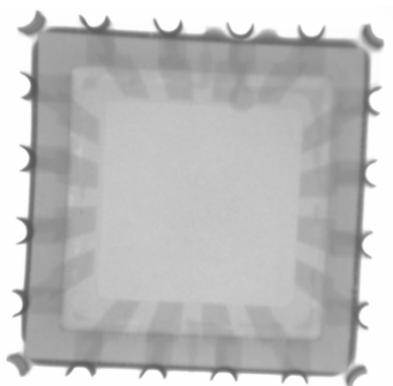
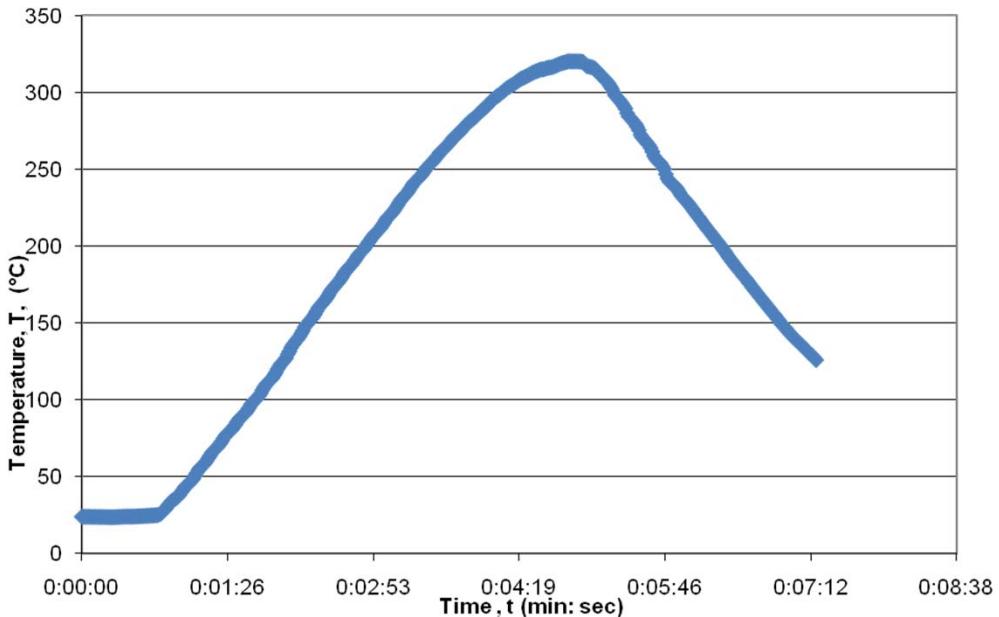
Trials were run with the compact furnace to identify the reflow recipe that yields the prescribed peak temperature profile, a structurally-sound hermetic lid seal, and the lowest cycle time.



Results

- 84% reduction in cycle time
- Peak temperature: 320°C.
- Void-free fillet
- Greatest leak rate observed was 1.3×10^{-9} atm-cm³/s.
- Standard: 9×10^{-8} atm-cm³/s after 60 seconds.

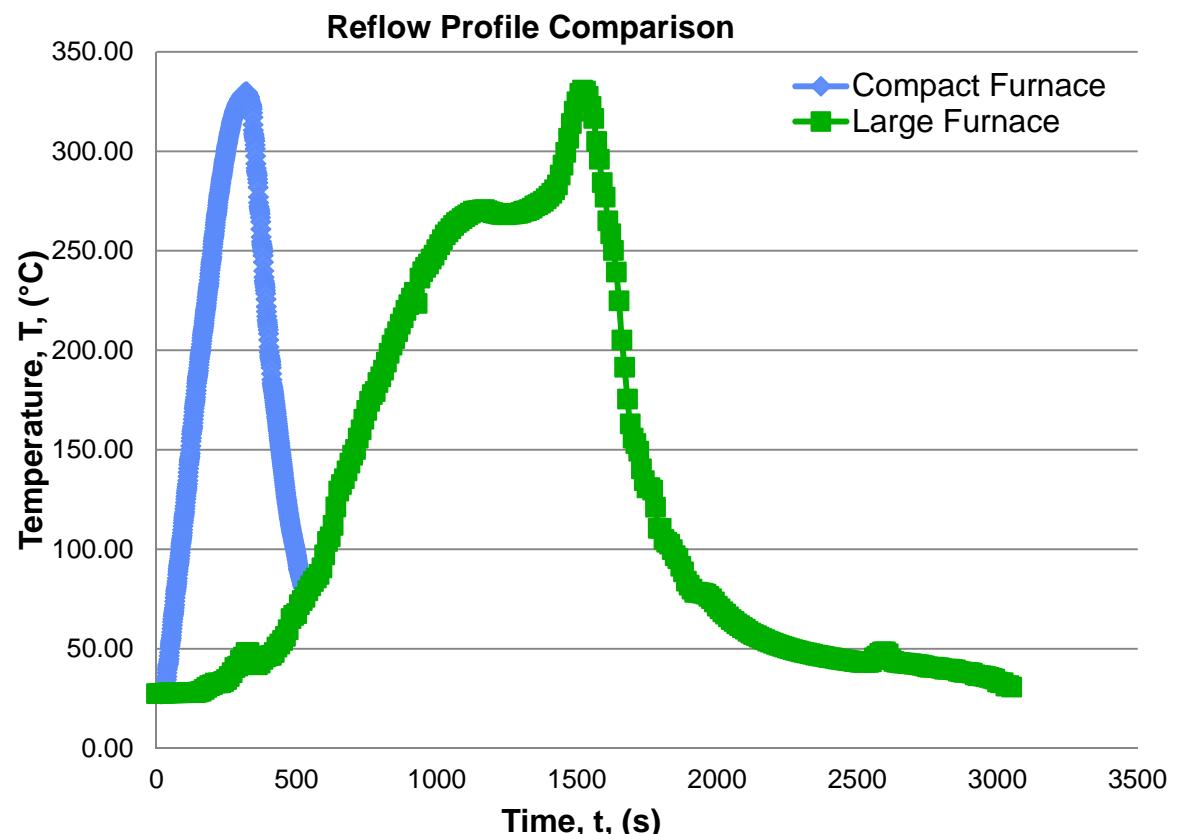
| Trial | Cycle Time (min: sec) | Peak Temp at LCC Lid (°C) |
|----------|--------------------------|------------------------------|
| 1 | 6:08 | 298 |
| 2 | 6:53 | 335 |
| 3 | 6:59 | 325 |
| 4 | 7:15 | 320 |
| 5 | 8:39 | 320 |
| 6 | 6:59 | 315 |
| 7 | 8:45 | 330 |





Comparing Reflow Platforms

- Large belt-style reflow furnace:
 - High throughput
 - Stable, repeatable
- Compact bench top system:
 - Lesser cycle time, greater productivity, lower labor cost
 - Lower capital investment (approximately \$25k US)
 - Lower peak input temperatures
 - More zones, higher rate of heat transfer



Trade throughput for lesser cycle time.



Conclusions and Future Work

- Hermetic lid sealing in this example is possible with the compact, dual-mode conduction/convection reflow furnace in a fraction of the cycle time relative to the larger apparatus.
- Actual peak temperature closer to control input
- Future work:
 - Impact of peak reflow temperature on device functionality, e.g. GaAs thermally-activated “sinking gates”¹
 - Measure true temperature at the lid seal.
 - Investigate repeatability.
 - Measure energy consumption.

Reference:

¹Canali, C., et al., “Gate metallization “Sinking” into the active channel in Ti/W/Au metallized power MESFET’s,” *Electron Device Letters*, 7 (3), 1986, pp. 185-187.